



Silicon Carbide power devices: Status, challenges and future opportunities

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Outline

- □ Material Advantages of SiC vs. Si
- Current status of SiC Devices
- What are the challenges going forward?
- IUNET contributions



SiC: why?



 Low channel mobility (SiC Higher working temperature (200°C), SiO2 interface)
 Present limit is packaging





in 4H-SiC MOSFETs with

 $B_v < 1kV$



SiC pushes the boundary of unipolar devices for high power voltages (B_v > 1kV)

SiC CAGR 2016-2020: 28%

(Yole Développement, August 2017)



Main players in the SiC device industry



Company	Location	2010 SiC Power Electronics Revenue (M\$)
Infineon	Germany	27.1
Cree	USA	19.7
STMicro	Italy	1.6
ROHM	Japan	1.1
others		3.7

Top 4 suppliers (93% of market)

Infineon and STMicroelectronics in Europe with 54% of market

(Yole Développement, May 2013)



Gate Stress bias (V)

Current status of SiC MOSFETs



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The first 1.2kV SiC MOSFET by ST The double trench by ROHM The CoolSiC Trench MOSFET by Infineon



Source

trench

Comparative analysis of driving approach and performance of 1.2 kV SiC MOSFETs, Si IGBTs, and normally-off SiC JFETs 2014

Invited paper

SiC power MOSFETs performance, robustness and technology maturity

A. Castellazzi et al., Microelectronics Reliability 58 (2016)

The World's First Trench-Type SiC MOSFET --Significantly reduced ON resistance minimizes size and power consumption in high-power devices including industrial equipment



n+

O

Drain

Infineon

2017

CoolSiC Trench MOSFET

Combining SiC Performance

di Bologna





The most recent news

- Much progress has been made in reducing SiC crystal defects in substrates
- ✓ The SiC/SiO₂ interface still needs to be improved to reduce interface states (nitridations but also other new treatments)

FUTURE TRENDS IN SIC POWER DEVICE TECHNOLOGY:

- The wafer diameter increase towards 200mm would reduce the cost of SiC MOSFETs to be competitive with Si devices in 5 years (...and will decrease defect density)
- Better understanding of the SiC device specific tradeoffs is required
- Continuous gain in SiC device reliability is needed

"CoolSiC[™] and major trends in SiC power device development" Roland Rupp, Infineon, INVITED ESSDERC 2017





"Nano-Electronics Roadmap for Europe: Identification and Dissemination"
→ Task 4.2 Smart Energy (Gaudenzio Meneghesso – IUNET)

- NEREID will define the strategy for a roadmap for those technologies that extend the field of application of semiconductor technologies by adding new functionalities or extend application range.
- Smart-energy technologies, falling under the denomination of "More than Moore", do not scale simply with geometrical size, and are widely diversified; therefore new metrics will have to be identified for the roadmap.

Roadmap and cost/benefit for WBS

- **2015 2018**
- Large wafer sizes, multi-wafer reactors
- New circuit topologies
- Novel device topologies (lateral vs vertical)
- Reliability and stability of WBS



IUNET in the KWIGSIC4AP Project

2016 ECSEL RIA Call Wide band gap Innovative SiC for Advanced Power

The major aim is to design and to prototype on *SiC based* highly integrated *power converters...*

- DCDC Converters for Automotive with half volume and weight of magnetic components, switching frequencies increased from 25 to 150-200Khz, and efficiencies up to 96%
- Intelligent Power Switches and Inverter for avionics featuring higher operating temperatures (250 °C) in comparison with the actual150-200°C
- Compact portable charger for electric vehicles featuring 50% less overall conversion losses at a10% less volume/weight in comparison with Si-based actual chargers





Main role of IUNET

STMicroelectronics - Catania

An innovative trench structure will be developed and adopted to **1.2÷1.7kV** MOSFETs.

Fabricated devices will be assembled in innovative packages able to emphasize device thermal behavior.

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Measure bias temperature instability (BTI) and lowfrequency noise to

• Evaluate the material defectiveness and its impact on the device performance.

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Use of modeling and simulation to:

- Understand breakdown phenomena and identify the short and long-time device Safe Operating Area
- Explore technology options to improve performance and reliability

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Use of state-of-the-art characterization techniques to

 Identify device failure modes and mechanisms and give in-depth insight for technological improvements
 Realize a test circuit capable of highlighting the device performance in real operating conditions.



IUNET in the **REACTION** Proposal

2017 ECSEL IA Call

First and European SiC Eigth Inches Pilot line



- Neither SiC nor GaN have a cost advantage with respect to silicon today, largely because of wafer costs.
- REACTION will push through the first worldwide 200mm Silicon Carbide (SiC) Pilot Line Facility for Power technology.
- The 200mm SiC Pilot Line will be located in the ST wafer fab of Catania (Italy), and it will share facilities with the current 6" line.



Main role of IUNET

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• Performance evaluation and understanding of threshold voltage drift during bias temperature instability (BTI) stress;

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- Evaluation of device stability in switching-mode and comparison of DUTs fabricated with different process options;
- Ab-initio simulations of defects and traps to identify energy, type of traps and activation mechanisms;

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- TCAD simulations of Power SiC devices aimed at the device structure optimization and accounting for the degradation effects;
- Identification of device failure modes and mechanisms for the development of a Robust and reliable Power SiC devices.

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